## √In the Claims:

Please cancel claims 1, 2, 5 and 42-67 without prejudice or disclaimer.

Please rewrite claims 3, 4, 6-10, 14-19, 22, 24, 26, 28-38, 40 and 41 as follows:

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- 3. (Amended) The piezoelectric/electrostrictive device according to claim 8, wherein said multilayered member is composed of ten or less of said actuator films.
- 4. (Amended) The piezoelectric/electrostrictive device according to claim 8, wherein each of said actuator films is formed by means of a thick film printing method.
- 6. (Amended) The piezoelectric/electrostrictive device according to claim 8, wherein said adhesive has a thickness of not more than  $15 \mu m$ .
- 7. (Amended) The piezoelectric/electrostrictive device according to claim 8, further comprising an underlying layer formed on a surface of said piezoelectric/electrostrictive element opposed to a respective one of said thin plate sections.
- 8. (Amended) A piezoelectric/electrostrictive device comprising:

at least one actuator section including a piezoelectric/electrostrictive element secured onto thin plate sections made of metal with an adhesive intervening therebetween, said at least one actuator section comprising a multilayered member including at least three or more actuator films each comprising a piezoelectric/electrostrictive layer and electrode films, wherein

one or more holes or recesses are formed in at least a portion of said thin plate sections on which said piezoelectric/electrostrictive element is formed.

- 9. (Amended) The piezoelectric/electrostrictive device according to claim 8, wherein at least a portion of a surface of each of said thin plate sections, on which said piezoelectric/electrostrictive element is formed, is a rough surface.
- 10. (Amended) A piezoelectric/electrostrictive device comprising a pair of mutually



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Didd Grad Grad opposing thin plate sections made of metal and, a fixation section for supporting said thin plate sections, and including an actuator section with a stacked type piezoelectric/electrostrictive element fixed on at least one of said thin plate sections by the aid of an adhesive, said stacked type piezoelectric/electrostrictive element comprising a plurality of piezoelectric/electrostrictive layers and electrode films, wherein said electrode films contact upper and lower surfaces of respective piezoelectric/electrostrictive layers and alternately extend to opposite end surfaces thereof, and end surface electrodes electrically connect an electrode film that contacts one of said piezoelectric/electrostrictive layers and an electrode film that contacts another one of said piezoelectric/electrostrictive layers, said end surface electrodes being electrically connected to terminals which are provided on a surface of an outermost layer of said piezoelectric/electrostrictive layers and which are separated from one another by a predetermined distance.

14. (Amended) A piezoelectric/electrostrictive device comprising:

a pair of mutually opposing thin plate sections, and a fixation section for supporting said thin plate sections; and

one or more piezoelectric/electrostrictive elements arranged on at least one thin plate section of said pair of thin plate sections, wherein

a minimum resonance frequency of said piezoelectric/electrostrictive device structure, which is obtained when an object member having a size substantially equivalent to that of said fixation section exists between open ends of said pair of thin plate sections, is not less than 20 kHz, and a relative displacement amount between said object member and said fixation section is not less than 0.5 µm at a substantial applied voltage of 30 V at a frequency which is not more than 1/4 of said resonance frequency.

- 15. (Amended) The piezoelectric/electrostrictive device according to claim 14, further comprising an adhesive intervening between said piezoelectric/electrostrictive element and said at least one thin plate section, said adhesive having a thickness which is not more than 10 % of a thickness of said piezoelectric/electrostrictive element.
- 16. (Amended) The piezoelectric/electrostrictive device according to claim 14, wherein said one or more piezoelectric/electrostrictive elements are arranged on one thin plate section

of said pair of thin plate sections, and a thickness of said one thin plate section is thicker than a thickness of the other thin plate section.

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- 17. (Amended) The piezoelectric/electrostrictive device according to claim 14, wherein said object member intervenes between said open ends of said pair of thin plate sections, and a distance of said pair of thin plate sections between a boundary portion of said object member and a boundary portion of said fixation section is not less than 0.4 mm and not more than 2 mm, and each of said pair of thin plate sections has a thickness which is not less than 10  $\mu$ m and not more than 100  $\mu$ m.
- 18. (Amended) The piezoelectric/electrostrictive device according to claim 14, wherein said piezoelectric/electrostrictive element comprises a multilayered member including at least three or more actuator films comprising piezoelectric/electrostrictive layers and electrode films.
- 19. (Amended) The piezoelectric/electrostrictive device according to claim 18, wherein said piezoelectric/electrostrictive element comprises said multilayered member having ten or less actuator films.

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22. (Amended) The piezoelectric/electrostrictive device according to claim 18, wherein said plurality of electrode films, which are included in said multilayered member for constructing said piezoelectric/electrostrictive element, are stacked alternately, and are connected so that an identical voltage is applied to every other electrode layer.

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24. (Amended) The piezoelectric/electrostrictive device according to claim 22, wherein one end of said electrode layer is formed at a position not including at least said fixation section as viewed in plan view.



26. (Amended) The piezoelectric/electrostrictive device according to claim 24, wherein said object member intervenes between said open ends of said pair of thin plate sections, and (1 - Lb/La) is not less than 0.4, wherein,

La represents a shortest distance of said pair of thin plate sections between a boundary

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portion of said object member and a boundary portion of said fixation section, and

Lb represents a shortest distance of said thin plate section on which said multilayered member is not formed from one of said object member and fixation member boundary portions between said thin plate sections to an end of said electrode film.

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- 28. (Amended) The piezoelectric/electrostrictive device according to claim 14, wherein said thin plate sections comprise a metal.
- 29. (Amended) The piezoelectric/electrostrictive device according to claim 28, wherein said thin plate sections comprise a metal plate subjected to a cold rolling process.
- 30. (Amended) The piezoelectric/electrostrictive device according to claim 18, further comprising an adhesive having a thickness of not less than 0.1  $\mu$ m and not more than 30  $\mu$ m intervening between said thin plate sections and said multilayered member for constructing said piezoelectric/electrostrictive element.
- 31. (Amended) The piezoelectric/electrostrictive device according to claim 30, wherein said adhesive comprises an organic resin.
- 32. (Amended) The piezoelectric/electrostrictive device according to claim 30, wherein said adhesive comprises glass, brazing material, or solder.
- 33. (Amended) The piezoelectric/electrostrictive device according to claim 30, further comprising an underlying layer formed on a surface of said multilayered member opposed to a respective one of said thin plate sections.
- 34. (Amended) The piezoelectric/electrostrictive device according to claim 30, wherein one or more holes or recesses are formed in at least a portion of said thin plate sections on which said multilayered member is formed.
- 35. (Amended) The piezoelectric/electrostrictive device according to claim 30, wherein at least a portion of a surface of each of said thin plate sections, on which said multilayered

member is formed, is a rough surface.

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- 36. (Amended) The piezoelectric/electrostrictive device according to claim 14, further comprising an adhesive having a thickness of not less than 0.1  $\mu$ m and not more than 30  $\mu$ m intervening between said thin plate section and at least said fixation section.
- 37. (Amended) The piezoelectric/electrostrictive device according to claim 36, wherein said adhesive comprises an organic resin.
- 38. (Amended) The piezoelectric/electrostrictive device according to claim 36, wherein said adhesive comprises glass, brazing material, or solder.

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- 40. (Amended) The piezoelectric/electrostrictive device according to claim 36, wherein an object member intervenes between open ends of said pair of thin plate sections, and at least an angular portion of said fixation section opposed to said object member is chamfered.
- 41. (Amended) The piezoelectric/electrostrictive device according to claim 36, wherein said thin plate section is manufactured by means of stamping of a metal plate, and a burr, which is brought about by said stamping, is directed outwardly.

## Please add new claims 68-72 as follows:

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- 68. (New) The piezoelectric/electrostrictive device according to claim 10, wherein said actuator section comprises ten or less of said piezoelectric/electrostrictive layers.
- 69. (New) The piezoelectric/electrostrictive device according to claim 10, wherein each of said stacked type piezoelectric/electrostrictive elements is formed by means of a thick film printing method.

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70. (New) The piezoelectric/electrostrictive device according to claim 10, wherein said adhesive has a thickness of not more than  $15\mu m$ .

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- 71. (New) The piezoelectric/electrostrictive device according to claim 10, further comprising an underlying layer formed on a surface of said stacked type piezoelectric/electrostrictive element opposed to a respective one of said thin plate sections.
- 72. (New) The piezoelectric/electrostrictive device according to claim 10, wherein at least a portion of a surface of each of said thin plate sections, on which said stacked type piezoelectric/electrostrictive element is formed, is a rough surface.